

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TETSUKA et al

Serial No.: 10/784,275

Filed: February 24, 2004

For: Plasma Processing Apparatus And Plasma
Processing Method

Art Unit: 1763

Examiner: R. Zervigon

AMENDMENT

Mail Stop: Amendment (No Fee)
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 1, 2007

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated May 1, 2007. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.